





















PREPARATION METHOD

MAGNESIUM BASED ALLOYS

 CUTTING		Equipment QATM Qcut / Brilliant	Consumable Cut-off wheel: diamond, resin bond Anti-corrosion coolant			
 MOUNTING		Equipment QATM Qpress / Opal	Consumable Bakelite red/black/green KEM 20	Method Hot mounting Cold mounting		
 GRINDING/ POLISHING		Equipment QATM Qpol / Saphir Sample size \varnothing 40 mm				
STEP	MEDIUM		 rpm		 N	 min
 Planar grinding	SiC-paper/foil* P320 (280)	H ₂ O	250-300	▶▶ Synchronous rotation	15	Until plane
 Planar grinding	SiC-paper/foil* P800 (280)	H ₂ O	250-300	▶▶ Synchronous rotation	15	1:00
 Planar grinding	SiC-paper/foil* P1200 (280)	H ₂ O	250-300	▶▶ Synchronous rotation	15	1:00
 Polishing	BETA	 Diamond suspension (alcohol or oil based) 9 μ m, poly	120-150	▶▶ Synchronous rotation	15	5:00
 Polishing	SIGMA	 Diamond suspension (alcohol or oil based) 3 μ m, poly	120-150	▶▶ Synchronous rotation	15	5:00
 Polishing	ZETA	 Diamond suspension (alcohol or oil based) 1 μ m, poly	120-150	▶▶ Synchronous rotation	15	5:00
 Final polishing	OMEGA**	Etosil E, 0.06 μ m	120-150	◀▶ Counter rotation	25	4:00 (ethanol during final 0:30)
 Optional: Final polishing	OMEGA / Qpol Vibro	Etosil E, 0.06 μ m	120-150			20:00
 Optional: Etching (chemical)	Nital 3%					Approx. 0:03-0:10 (ethanol 0:30)

* Coat grinding paper/foil with paraffin wax before grinding to reduce the contamination of the sample by SiC particles

** Wet the polishing cloth with ethanol before polishing